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THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/677,478
Filing Date October 2, 2000
Inventor Guy T. Blalock
Assignee Micron Technology, Inc.
Group Art Unit 1765
Examiner Lan Vinh
Attorney's Docket No. MI22-1544
Title: Plasma Etching Methods

RESPONSE TO MARCH 29, 2002 OFFICE ACTION

To: Box Fee Amendment
Assistant Commissioner for Patents
Washington, D.C. 20231

From: D. Brent Kenady (Tel. 509-624-4276; Fax 509-838-3424)
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RECEIVED
JUL 31 2002
TECHNOLOGY CENTER**AMENDMENTS****In the Specification**

At page 1, before the "Technical Field" section, please replace the existing Related Applications section with the following:

--RELATED PATENT DATA

BI
This patent is a continuation application of U.S. Patent Application Serial No. 09/141,775, which was filed on August 27, 1998, entitled "Plasma Etching Methods", naming Guy T. Blalock, David S. Becker and Kevin G. Donohoe as inventors, and which is now U.S. Patent No. 6,277,759, the disclosure of which is incorporated by reference.--